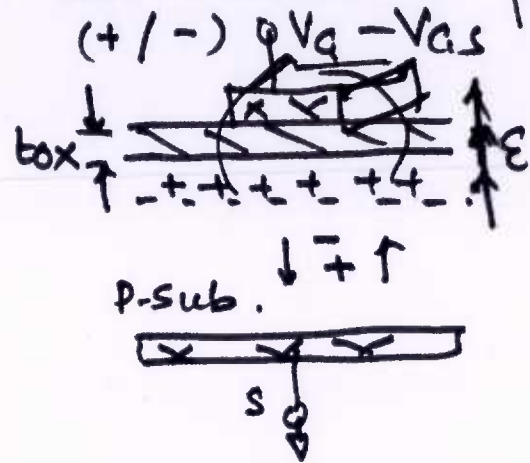


MOS Capacitor is a simple device which can be used to evaluate almost all electrical properties of  $\text{SiO}_2$ -Si system.



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$$\epsilon = K \epsilon_0$$

(i)  $V_{gs}$  is -ve (Accumulation Mode) EE 669 L 13 / Slide 08

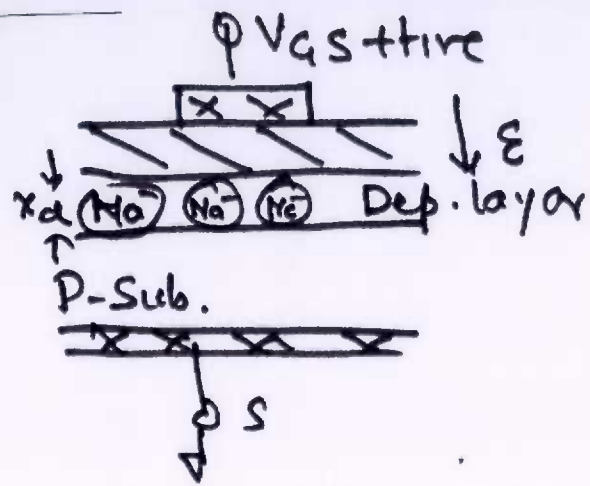
Electrons are repelled from  $\text{SiO}_2$ -Si interface. This creates excess holes at that place.

Thus interface accumulates holes (+tive charge).  $-Q_m$  at the metal =  $Q_{si}$  at surface (Gauss's law  $Q_m + Q_s = 0$ )

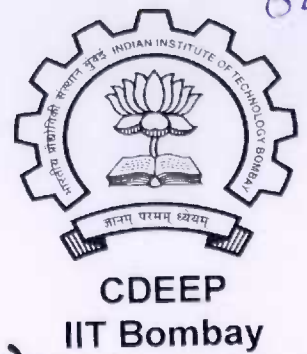
The capacitor has now like metal-oxide-metal structure with  $C = C_{ox} \cdot A$  where  $C_{ox} = \frac{\epsilon_{ox}}{t_{ox}}$  F/cm<sup>2</sup>

iii)  $V_{gs}$  is +tive but small (Depletion Mode)





In getting Gauss's law statement, we assume here that there are no charges in Oxide and hence  $\epsilon_{ox} E_{ox} = \epsilon_s E_s$  (Discontinuity) is followed.



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With  $V_{gs}$  small positive, we have  $Q_m$  + & small. Gauss's law not want -ve charges to reach surface of Silicon. Direction of Electrical field forces holes to move downwards leaving -ve Acceptor ions at Si-Surface. That is surface region gets depleted of free carriers, and one observes Depletion Region. The depletion width  $\propto \sqrt{V_{gs}}$   $= -q N_a x_d$

Initially due to small  $V_{gs}$ ,  $\propto 1/\sqrt{N_a}$   $x_d = \sqrt{\frac{2\epsilon_s \phi_b}{q N_a}}$   
 Electric field  $E_s$  is also small. Hence Generation of e-h pair in D.Layer, finally recombine there it self.

We have now two capacitors in series

$$\begin{aligned} & \text{Top capacitor: } C_{ox} \cdot A = C'_{ox} \\ & \text{Bottom capacitor: } C_s \cdot A = C'_s \end{aligned}$$

Hence net  $C = \frac{C'_{ox} C'_s}{C'_{ox} + C'_s}$

Obviously net  $C$  now will be less than  $C'_{ox}$  as was observed in Accumulation case.

iii) Hence increase in  $+V_{gs}$  will decrease  $C_s$  as depletion width will enhance. This means  $C_{net}$  will decrease further with  $V_{gs}$  increasing.



iii)  $V_{gs}$  Positive and large (Inversion)

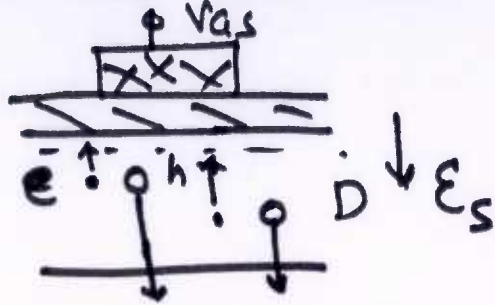
At some reasonably high  $V_{gs}$ , Electric Field in Semiconductor region becomes sufficiently <sup>high</sup>, that is  $E_s$  become large enough, then generated electron-hole pairs experience large force and they separate. Holes move along the field come out of Depletion layer and are collected at Sub-ground



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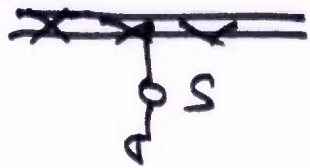
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While electrons



move towards surface. The starting wafer has p-type doping, so without Bias Silicon Surface was p-type with hole conc.  $= N_A$

However now electrons start



Piling up at Si-surface opposite to starting case (hole conc.). This case is called Inversion.

Since excess  $V_{gs}$  now creates free inversion electrons, Depletion layer remains constant and hence net Capacitor also becomes const independent of  $V_{gs}$ .

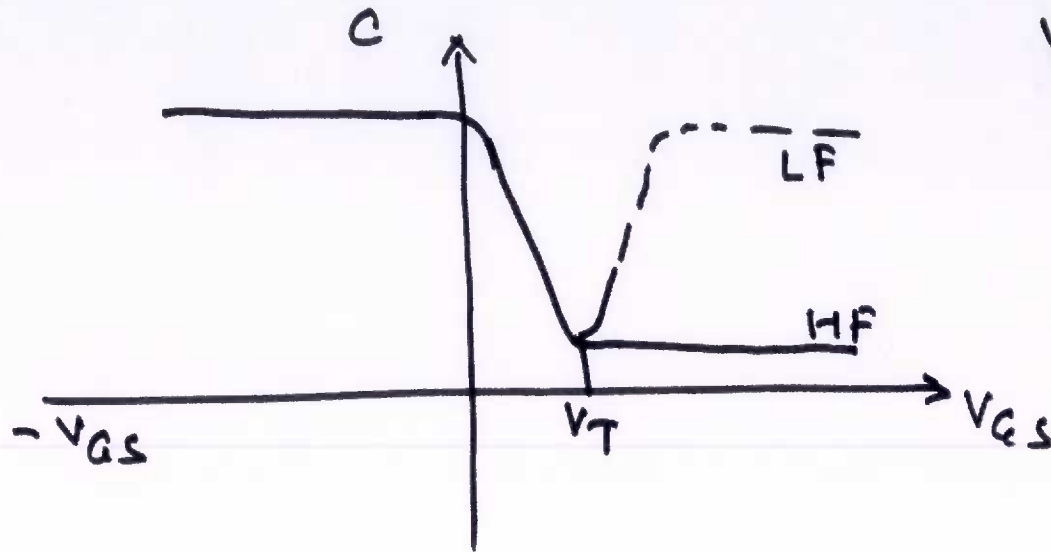
The value of  $V_{gs}$  (Positive for P-sub), at which inversion electron conc.  $n$  is equal to starting p-conc, is called Threshold Voltage  $V_T$ .



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$$V_s = V_{ox} + \psi_s$$



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Ideally  $V_T = \pm 2\phi_F - \frac{\pm Q_{Bulk}}{C_{ox}}$

where  $Q_{Bulk}$  is Depletion charge density

$$= +q N_d^+ x_{dmax}$$

$$\text{or} = -q N_a^- x_{dmax}$$

and  $\phi_F$  is Fermi Energy &  $\phi_F = \pm \frac{kT}{q} \ln \frac{N_a (\text{or } N_d)}{n_i}$   
 $= E_i - E_F$

In real life



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$$V_T = \phi_{ms} \pm 2\phi_F - \frac{Q_{ox}}{C_{ox}} - \frac{\pm Q_B}{C_{ox}}$$

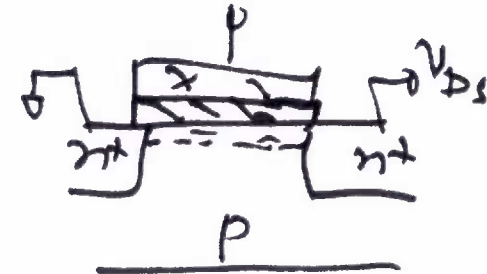
$\phi_{ms} = \phi_m - \phi_s$  Work function Difference  
between Metal & Semiconductor

$Q_{ox}$  = fixed Oxide Charge (~~Always~~ Always Positive)

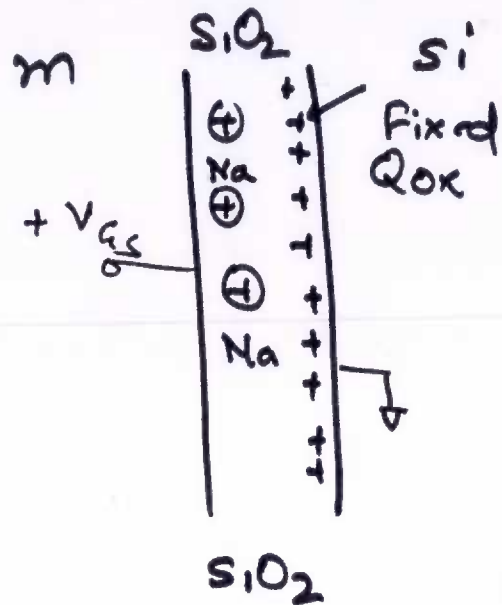
$$\phi_F = \text{Fermi Potential} = \frac{E_i - E_F}{q}$$

Mos Sat Current  $\Rightarrow$

$$I_{Dsat} = \frac{1}{2} \mu C_{ox} \left( \frac{W}{L} \right) [V_{GS} - V_T]^2 [1 + \lambda V_{DS}]$$



Fixed charge  $Q_{ox}$  : —



within  $25 \text{ \AA}$  of  $Si-SiO_2$  surface, we observe that a +tive charges exist and their Density is almost constant.

This Charge Density  $Q_{ox} (q/cm^2)$  is attributed to fact that at the end of oxidation time, interface proximity leaves incomplete oxidation and may end up in  $Si^{3+}-O$  bonds, which results in Fixed Positive charge.  $Q_{ox\text{Fixed}} \approx 9 \cdot (10^{10} - 10^{11}) \text{ col./cm}^2$

Mobile Charge :— Sodium ions ( $Na^+$ ) are omnipresent in  $SiO_2$  and they can drift in Oxide under electric field. Mobile charge density  $Q_{Mobile}$  is varying function



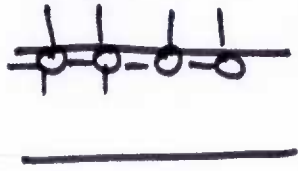
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# Interface Charge

Any Solid Surface, leaves dangling bonds which are not satisfied.

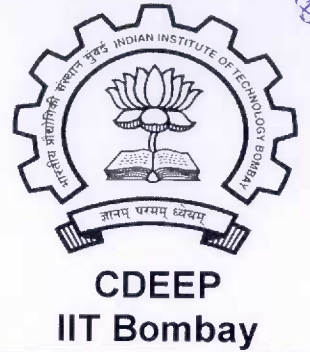
D.B.



Silicon Surface too, however cleaned (Virgin surface), also have these

Dangling Bonds present. These are called Schokly or Tamm States. The number of Such States could be as high  $10^{20}/\text{cm}^2$

During Oxidation of Silicon, Oxygen tries to Bond with Silicon through these bonds, reducing their charge density. However not all bonds are Satisfied and leaves interface charge density of the order of  $q \cdot x(10^{10} - 10^{11}) \text{ col/cm}^2$ . Number Density is termed  $D_{it}$   
 $\therefore Q_{it} = q \cdot D_{it}$ .



# Influence of Interface charges of MOS Device characteristics.

For a MOS Capacitor (or MOS Transistor) the threshold voltage  $V_T$  is given by

$$V_T = \phi_{ms} \pm 2\phi_F - \frac{Q_{ox} + Q_{it} + Q_m}{C_{ox}} - \frac{\pm Q_{Bulk}}{C_{ox}}$$

where  $\phi_{ms} = \phi_m - \phi_s$

$$Q_{Bulk} = \pm q (N_a \text{ or } N_d) x_{dmax}$$

$$2\phi_F = 2 \cdot \text{Fermi Potential} = \frac{2kT}{q} \ln \frac{N_a \text{ (or } N_d)}{n_i}$$

$$x_{dmax} = \sqrt{\frac{2K_s \epsilon_0 \psi_s}{q N_a \text{ (or } N_d)}}$$

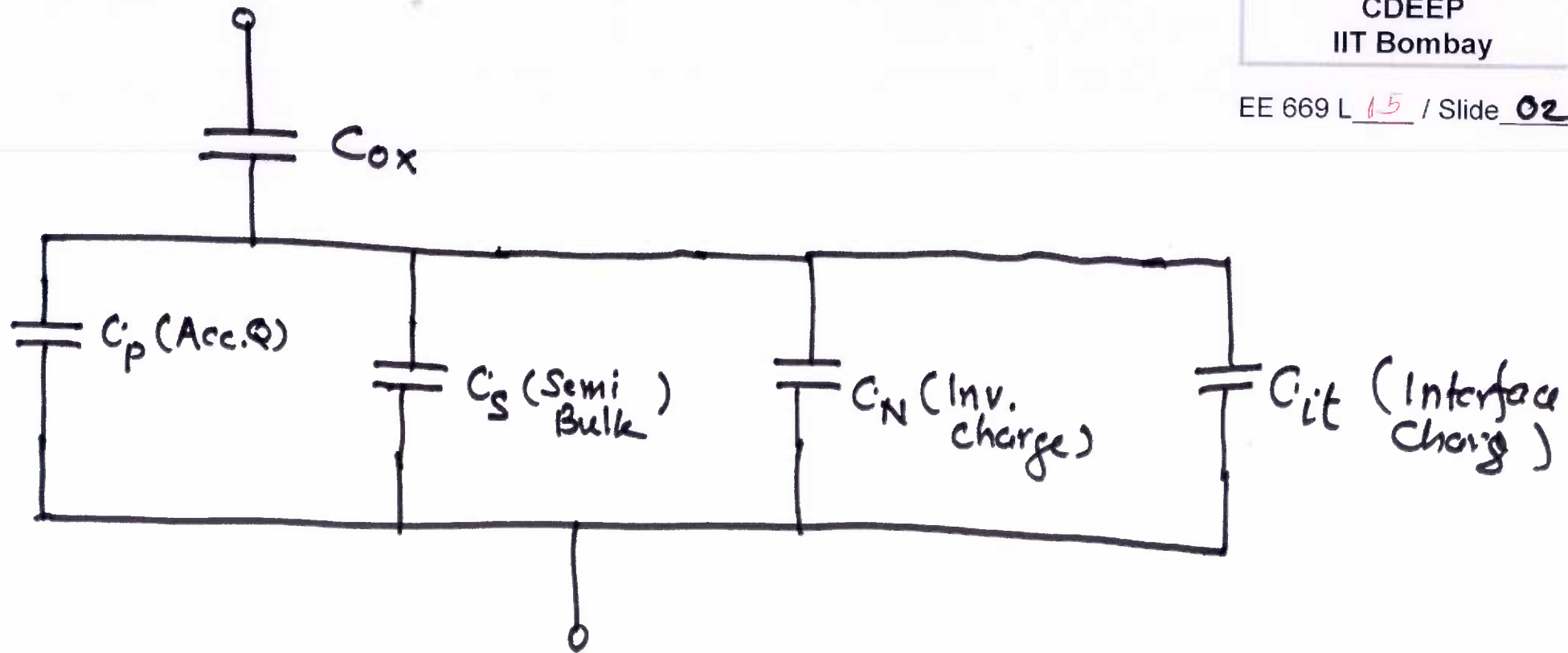
$\psi_s$  is Surface Potential and  $\psi_s = 2\phi_F$  at Inversion



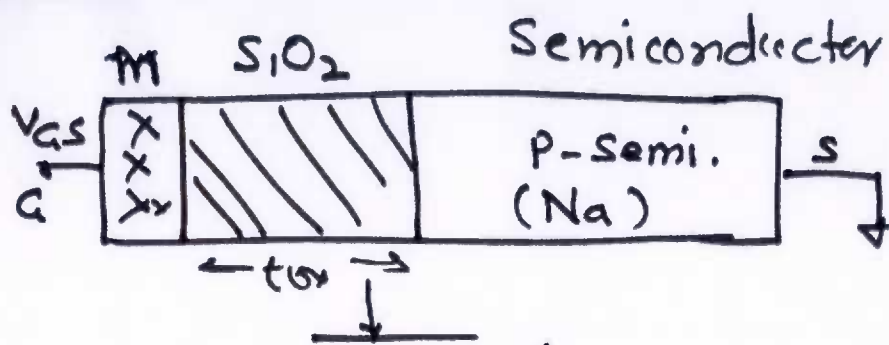
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Typical Equivalent Circuit of a MOS capacitor  
can be : We define  $C = \frac{dQ}{dV_{GS}}$ , Then  
C is  $\rightarrow$

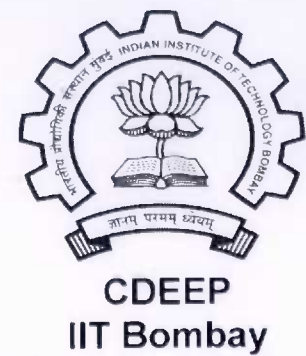


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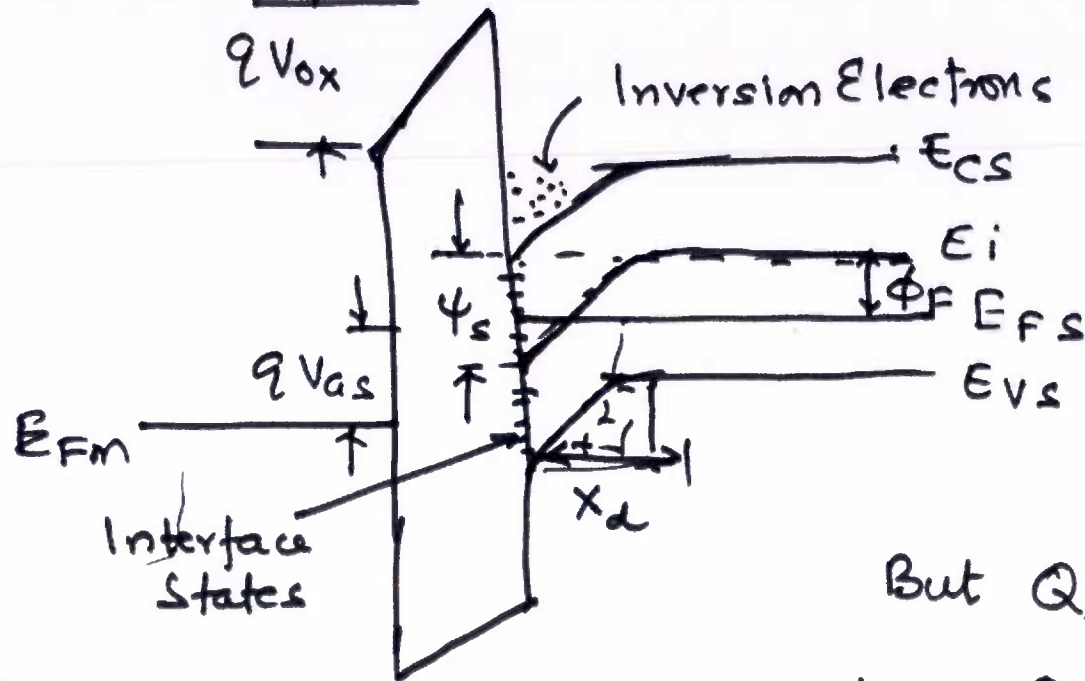


$$p = n_i \exp\left(\frac{E_i - E_F}{kT}\right)$$

$$n = n_i \exp\left(\frac{E_F - E_i}{kT}\right)$$



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We know

$$C = \frac{dQ}{dV} \quad \left\{ \begin{array}{l} Q - \text{Charge/cm}^2 \\ C = \text{F/cm}^2 \end{array} \right.$$

$$C_{ox} = \frac{dQ_G}{dV_{GS}}$$

But  $Q'_S = -Q_G - Q_B = \text{Interface charge}$   
 where  $Q_G$  is Gate Charge density

$$\text{or } Q_G = -(Q'_S + Q_B) = -(Q'_S + Q_B)$$

$$V_{GS} = V_{ox} + \psi_s$$

$$\epsilon_s \epsilon_s = \epsilon_{ox} \epsilon_{ox}$$

But if D is continuous

$$\text{or } \epsilon_s \epsilon_s = \frac{\epsilon_{ox} V_{ox}}{t_{ox}}$$

$$\therefore V_{ox} = \frac{\epsilon_s \epsilon_s}{Q_{ox}/t_{ox}} = \frac{\epsilon_s \epsilon_s}{C_{ox}}$$

But  $Q_s = -\epsilon_s \epsilon_s$  By Gauss's Law

$$\therefore V_{ox} = -\frac{Q_s}{C_{ox}}$$

$$\therefore V_{GS} = \psi_s - \frac{Q_s}{C_{ox}}$$

At  $V_{GS} = V_T$        $\psi_s = 2\phi_F$

$$\therefore V_T = 2\phi_F - \frac{Q_s (=Q_B)}{C_{ox}}$$

Where  $Q_s = Q_B =$  Depletion Charge density

$$\begin{cases} = +qN_d^+ x_{dmax} & \rightarrow n\text{-sub} \\ = -qN_a^- x_{dmax} & \rightarrow p\text{-sub} \end{cases}$$

$$\therefore V_{Tn} = 2\phi_F + (qN_a x_{dmax} / C_{ox})$$



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